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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Akihisa HONGO et al.

Serial No. 09/842,650

Filed April 27, 2001

REVOLUTION MEMBER SUPPORTING
APPARATUS AND SEMICONDUCTOR
SUBSTRATE PROCESSING APPARATUS

: Confirmation No. 7681

: Docket No. 2001_0519A

: Group Art Unit 1763

: Examiner S. Macarthur

: Mail Stop: AF

RESPONSE UNDER 37. CFR 1.116
SPECIATED PROCEDURE
EXAMINING GROUP 1763

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE EXPENDITURE IN THE
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ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of May 20, 2004, please amend the above-identified U.S. Patent application as follows: